

# Poster Presentations

- Transient light-induced refractive index change in nitroaniline-doped PMMA film made by laser microfabrication**, A. Yamasaki, S. Juodkazis, M. Watanabe, S. Matsuo, H. Misawa, Tokushima University, K. Kamada, K. Ohta, Osaka National Research Institute (Japan) [4088-065]
- Pulsed laser nitridation of InP surface**, N. Aoki, K. Toyoda, Science University of Tokyo, Toshimitsu Akane<sup>A</sup>, Koji Sugioka, Katsumi Midorikawa, RIKEN (The Institute of Physical and Chemical Research); J.J. Dubowski, National Research Council of Canada. (Japan) [4088-067]
- Effects of laser pulse shape on jet-like plasma formation in laser ablation of metals under atmosphere at high fluence: observation by nanosecond imaging technique**, S. Kiyoku, Y. Kurosaki, I. Oguro, S. Nakamura, Y. Ito, Nagaoka University of Technology (Japan) [4088-069]
- Molecular dynamics analysis on physical phenomena of metal with evaporation induced by laser irradiation**, I. Fukumoto, Japan Atomic Energy Research Institute; E. Ohmura, I. Miyamoto, Osaka University (Japan) [4088-070]
- A Technique of Micromachining Suitable For Fabrication of Submillimeter Wave Components**, W.Y. Liu, D.P. Steenson, University of Leeds (UK) [4088-071]
- Improving the Dimensional Accuracy of Laser Shaping by Using a High-resolution contact lithography by excimer lasers**, H. Huang, D. Lu, L. Du, Y. Zhao, C. Yuan, B. Jiang, R. Wang, Shanghai Institute of Optics and Fine Mechanics, Chinese Academy of Sciences (China) [4088-073]
- Inorganic-organic hybrid material for lithography**, P. Lin, Y. Yan, G. Jin, M. Wu, State Key Laboratory of Precision Measurement Technology and Instruments (China) [4088-074]
- The etching characteristics of the PDP barrier rib pastes by focused Ar<sup>+</sup> laser and Nd: YAG laser**, C. Lee, K.C. Lee, M.y. Ahn, H.g. Lee, IN-HA University (Korea) [4088-075]
- Thermomechanical mechanisms of laser cleaning**, V.P. Veico, E.A. Shakhno, S.V. Nikolaev, Saint-Petersburg Federal Institute of Fine Mechanics and Optics, Technical University (Russia) [4088-076]
- N<sub>2</sub> laser stereo-lithography**, S. Satoh, Saga University(Japan) [4088-077]
- Through-hole drilling of glass substrates with slab waveguide CO<sub>2</sub> laser**, Y. Yoshida, Y. Kobayashi, T. Zhang, Yamanashi University; H. Yajima, Y. Hashidate, H. Ogura, Matsushita Research Institute of Tokyo Inc.(Japan) [4088-078]
- High repetition rate ArF excimer laser for microlithography**, O. Wakabayashi, Y. Itakura, T. Watanabe, T. Ohta, A. Ohbu, H. Kubo, T. Suzuki, A. Sumitani, H. Mizoguchi, T. Enami, K. Ishii, K. Terashima, H. Tanaka, Komatsu Ltd. (Japan) [4088-080]
- Thermodynamic analysis on the mechanism of bump formation in laser texturing**, E. Ohmura, R. Murayama, I. Miyamoto, Osaka University (Japan) [4088-082]
- Laser surface annealing of Ni-base super alloy for enhancement of material performance in hydrogen environment**, A. Hirose, L. Liufa, F.K. Kobayashi, Osaka University (Japan) [4088-084]
- Mechanisms of laser induced formation of silicon surface gratings**, C.Y. Chen, C.C. Yang, National Taiwan University; K.J. Ma, Y.S. Lin, C.L. Chao, Chung-Cheng Institute of Technology (Taiwan) [4088-085]
- Surface grating of glass materials by excimer laser**, I.T. Chen, K.J. Ma, C.L. Chao, D. S. Liu, Chung-Cheng Institute of Technology (Taiwan) [4088-086]
- Numerical simulation of temperature field during laser sintering of polymer-coated metal powder**, P. Bai, North China Institute of Technology (China) [4088-087]
- New interferometric methods to measure the complete geometry of the key-hole**, M. Muddassir, S. Gualini, H. Steinbichler, Pakistan Institute of Lasers and Optics (Pakistan) [4088-089]
- Plasma behaviors in laser cutting**, H. Horisawa, M. Tamura, S. Kimura, Tokai University (Japan) [4088-090]
- Micro soldering using YAG laser**, S. Nakahara, T. Kamata, K. Yoneda, S. Hisada, T. Fujita, Kansai University (Japan) [4088-091]
- A fundamental study about molten metal of laser cutting**, T. Fushimi, H. Nakajima, S. Yamaguchi, T. Fujioka, H. Horisawa, N. Yasunaga, Tokai University (Japan) [4088-092]
- Fundamental study of CO<sub>2</sub> laser welding of titanium aluminide intermetallic compound**, G. Kuwahara, S. Yamaguchi, K. Nanri, M. Ootani, S. Seto, M. Arai, T. Fujioka, Tokai University (Japan) [4088-093]
- Effect of nozzle shape on surface integrity in micro cutting with pulsed YAG laser**, Y. Okamoto, Y. Uno, Department of Mechanical Engineering, Okayama University; N. Miyanagi, Hitachi Construction Machinery Co., Ltd. (Japan) [4088-094]

- A method to evaluate Nd: YAG laser microscopic spot welding process using reflected Laser power**, S.J. Park, R. Honma, I. Miyamoto, Osaka University (Japan) [4088-095]
- Study of optical emission of plasmas in ultraviolet and infrared laser ablation of graphite by time-resolved spectroscopy**, T. Shinozaki, T. Ooie, T. Yano, M. Yoneda, Shikoku National Industrial Research Institute (Japan) [4088-096]
- Three dimensional micro-assembling technique applying laser trapping**, D. Sawaki, O. Horiuchi, Toyohashi University of Technology; J. Ikeno, T. Kasai, Saitama University (Japan) [4088-097]
- Optical diagnostics in laser-induced plasma-assisted ablation of fused quartz**, M.H. Hong, Y.F. Lu, Laser Microprocessing Laboratory, National University of Singapore (Singapore); K. Sugioka, K. Midorikawa, RIKEN (Institute of Physical and Chemical Research) (Japan) [4088-098]
- Photo-induced refractive index changes in filaments formed in glasses with femtosecond laser pulses**, K. Yamada, T. Toma, W. Watanabe, J. Nishii, K. Itoh, Osaka University (Japan) [4088-099]
- In vivo results of corneal surface measurement with optical methods**, M. Muddassir, S. Gualini, H. Steinbichler, Pakistan Institute of Lasers and Optics (Pakistan) [4088-100]
- Removal Process of Metal Thin Films during Laser Rear Patterning**, T. Sano, I. Miyamoto, Osaka University (Japan) [4088-101]
- Application of optic registration techniques of gas jet for a laser-plasma EUV source investigation**, V.V. Askov, S.V. Bobashev, T.G. Kopitova, A.A. Schmidt, Z.A. Stepanova, G.K. Tumakaev, Ioffe Institute (Russia) [4088-102]
- A laser method for marking bar codes on glass substrates**, H. Hayakawa, YASKAWA Electric Corporation Research Laboratory (Japan) [4088-103]
- Laser processing system for micro drilling of printed circuit boards**, J. Nishimae, Y. Satoh, T. Kojima, T. Fukushima, Mitsubishi Electric Corporation (Japan) [4088-104]
- Development of the enhanced in-line concurrent inspection system for CO<sub>2</sub> laser drilling machine**, H. Nagatoshi, K. Isaji, T. Sugiyama, H. Karasaki, Matsushita Industrial Equipment Co., Ltd.; M. Kato, Matsushita Electric Industrial Co., Ltd. (Japan) [4088-106]
- Selective Laser Sintering with Heat of Formation by Using Reactive Materials**, T. Kamitani, O. Yamada, Y. Marutani, Osaka Sangyo University (Japan) [4088-107]
- Compact tip/tilt laser scanner for material processing and biomedical applications**, M. Hafez, T. Sidler, and R.P. Salathe, Institute of Applied Optics (IOA) Swiss Federal institute of Technology (Switzerland) [4088-108]
- Micro-cutting with pulsed fundamental mode Nd-YAG slab laser**, T. Sidler, S. Favre, S. Benjamin, R.P. Salath, Swiss Federal Institute of Technologies (Switzerland) [4088-109]
- Laser micro processing unit and its application**, K. Fukumitsu, T.Oie, Hamamatsu Photonics K.K (Japan) [4088-111]
- Micro Materials Processing with High Power Diode Lasers**, F. Bachmann, ROFIN-SINAR Laser GmbH, (Germany); R. Takahashi, S. Fujishima, ROFIN-Marubeni Laser K.K.; (Japan) [4088-113]
- Applications of pulsed lasers in low temperature thin film electronics fabrication**, T.W., Sigmon, D, Toet, P.G. Carey, P. M. Smith, P. Wickboldt, Lawrence Livermore National Laboratory (USA) [4088-014]
- Research on Laser Texturing Process and Surface Quality Control**, J. Jiang, School of Electronics & Information Technology; Y. He, Y. Yan, Y. Xu, Technical Center of ShangHai BaoSteel Group Corp; W. Zhao, Halbin Institute of Technology (China) [4088-041]